APPLICATION DATA SHEET

Electronic Version 0.0.11

Stylesheet Version: 1.0

Attorney Docket Number: 740756-2651

Publication Filing Type:

new-utility

Application Type:

utility

Title of Invention:

LASER APPARATUS, LASER IRRADIATION METHOD, AND

MANUFACTURING METHOD OF SEMICONDUCTOR DEVICE

Suggested Representative Figure:

Fig. 1

Legal Representative:

Attorney or Agent:

Jeffrey L. Costellia

Registration Number:

35483

Customer Number Correspondence Address:

22204

22204

Foreign Priority:

2002-269655

JP 2002-09-17

Priority Claimed

Assignee (Publish): Semiconductor Energy Laboratory Co., Ltd.

398, Hase

Atsugi-shi 243-0036 Kanagawa-ken JP

INVENTOR(s):

Primary Citizenship:

Japanese

Given Name:

Hidekazu

Family Name:

MIYAIRI

Residence City:

Tochigi, Tochigi

Residence Country:

JP

Address:

c/o Semiconductor Energy Laboratory Co., Ltd., 398,

Hase

Atsugi-shi Kanagawa-ken, 243-0036 JP

Primary Citizenship:

Japanese

Given Name:

Akihisa

Family Name:

SHIMOMURA

Residence City:

Atsugi, Kanagawa

Residence Country:

JP

Address:

c/o Semiconductor Energy Laboratory Co., Ltd., 398,

Hase

Atsugi-shi Kanagawa-ken, 243-0036 JP

Primary Citizenship:

Japanese

Given Name:

Tamae

Family Name:

TAKANO

Residence City:

Atsugi, Kanagawa

Residence Country:

JP

Address:

c/o Semiconductor Energy Laboratory Co., Ltd., 398,

Hase

Atsugi-shi Kanagawa-ken, 243-0036 JP

Primary Citizenship:

Japanese

Given Name:

Masaki

Family Name:

KOYAMA

Residence City:

Atsugi, Kanagawa

Residence Country:

JΡ

Address:

c/o Semiconductor Energy Laboratory Co., Ltd., 398,

Hase

Atsugi-shi Kanagawa-ken, 243-0036 JP